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U.S. Department of Commerce Patent and Trademark Office	APPLICANT Shichi et al	
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U.S. Patent Documents

Examiner Initial	Cited by Examiner in Parent	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
CMC	X	6,039,000	3/21/2000	Libby et al.			2/11/98
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CMK	X	L.R. Herlinger, S. Chevacharoenkul, D.C. Erwin, "TEM Sample Preparation Using a Focused Ion Beam and a Probe Manipulator", Proceedings of the 22 nd International Symposium for Testing and Failure Analysis, 18-22 November 1996, pp. 199-205
CMK	X	"Electron and Ion Beam Handbook", Third Edition, (Japan Society for the Promotion of Science, 132 commission, Nikkan Kogyo ShinbunSha), pp. 458-461
EXAMINER	Chris Kalwood	DATE CONSIDERED
04/23/04		
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